

Fully-Automatic Vacuum Mounter

RAD-2512F/12



Facility

Power Supply	Voltage	: AC200-230V ±10% (AC190-253V)
	Frequency	: 50/60Hz
	Phase	: single phase
Air Supply	Power consumption	: 4.0kW
	Air pressure	: 0.6-0.8MPa
	Air consumption	: >800L/min (ANR)
Vacuum Supply (for workpiece) (for vacuum chamber)	Vacuum pressure	: >-80kPa
	Ultimate Pressure	: 1.0Pa
	Pumping Speed	: >250L/min

Applicable Wafer Size 200mm (*300mm capability as option)

Size
Width : 2,203mm
Depth : 3,092mm
Height : 1,800mm
(excluding the signal tower and protruding parts)

Outline

- Fully-automatic wafer mounter equipped with a pre-cut tape mounting function in a vacuum environment.
- By using our unique vacuum control method, wafer mounting is performed without any contact with wafer surface.
- By adopting the non-contact wafer backside handling method, contamination of wafer is prevented.

- Options**
- Host Communication Function (Communication Format: Conforms to SECS-I and HSMS/Software: Conforms to GEM)
 - Vision System (Wafer ID Reader & Barcode Attachment System)
 - Dicing Tape In-line Pre-cutting

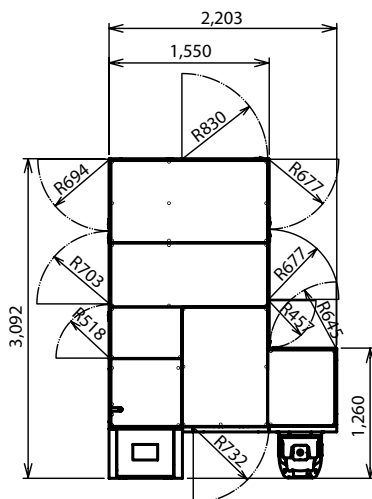
Weight 2,600kg

UPH 40wafers/hour

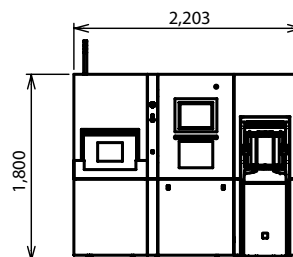
The above processing capacity is based on following conditions:
 Wafer : 200mm diameter non-polished mirror wafer
 Ring frame : for 200mm wafer
 Dicing tape : D-184 from LINTEC

Suitable Tape • Dicing tape: Adwill D series, G series

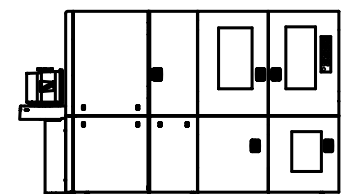
External View



Top View



Front View



Right Side View

Unit:mm



LINTEC Corporation *Linking your dreams*

● Head Office: 23-23 Honcho, Itabashi-ku, Tokyo 173-0001, Japan

Contact: Advanced Materials Operations 8th Fl, Bunkyo Garden Gate Tower, 1-1-1 Koishikawa, Bunkyo-ku, Tokyo 112-0002, Japan
 TEL. +81-3-3868-7737 FAX. +81-3-3868-7726

<https://www.adwill-global.com/en>